Supporting Information

Morphological and Molecular Control of oCVD Polythiophene Thin Films

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UV-Vis absorption

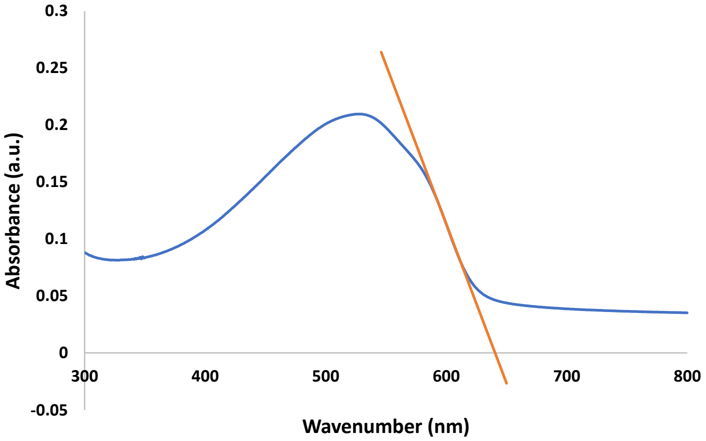

Figure S1: UV-Vis absorption spectra of oCVD PT film deposited on a plain silicon substrate at 150 mT. The tangent to the band edge or the absorption edge wavelength (λ_{ab}) is 640.51 nm and the optical band gap is given by $E_g = hc/\lambda_a = 1.94$ ev.

Morphology

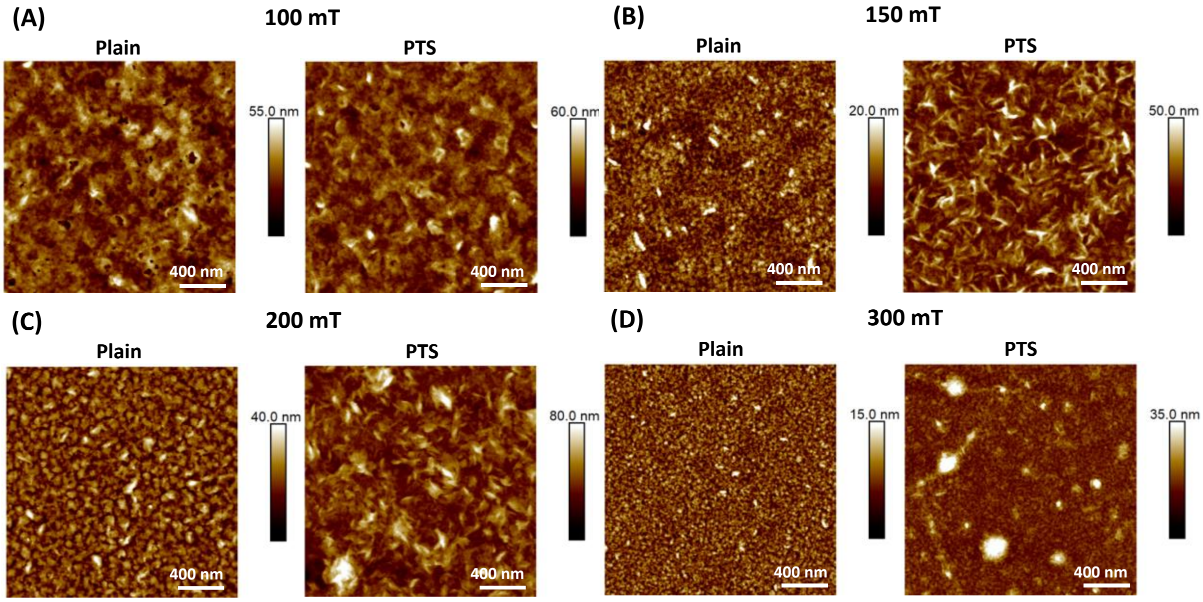

Figure S2: 2 µm x 2 µm AFM scans of oCVD PT films deposited on plain and PTS substrates at different deposition pressures.

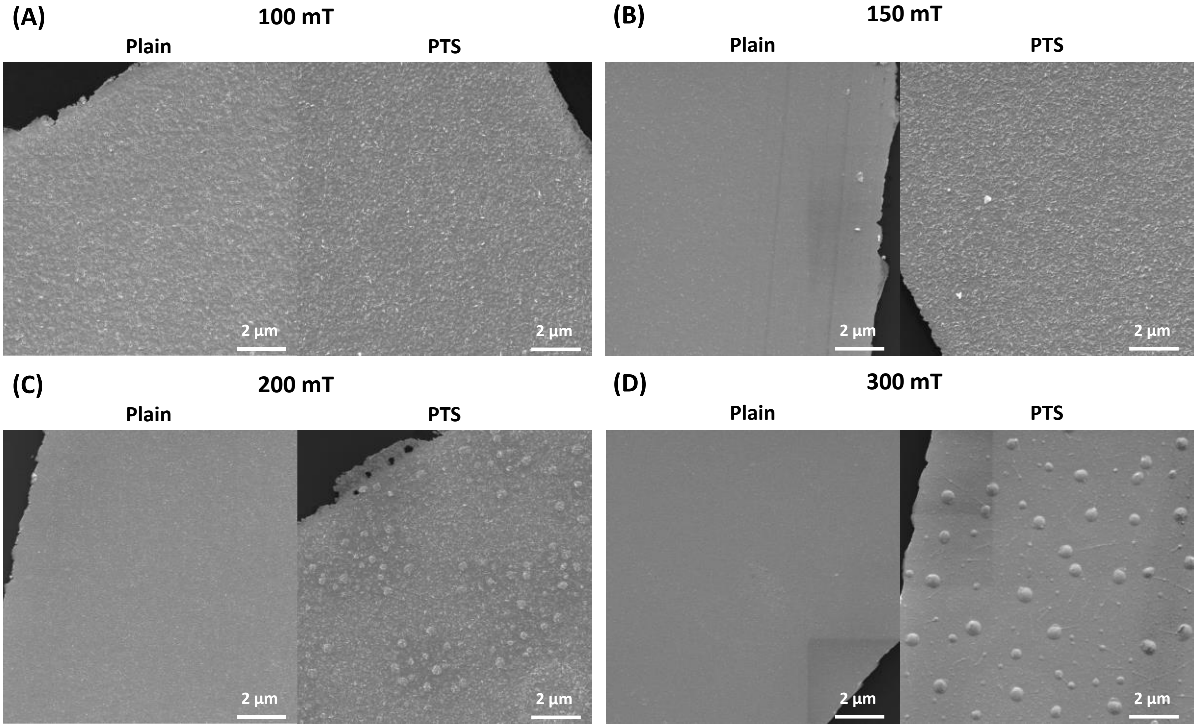

Figure S3: SEM images of oCVD PT films deposited on plain and PTS substrates at different deposition pressures.